**Advanced Workshop on Semiconductor Manufacturing**
**19th November to 1st December 2026**
Centre for Nano Science and Engineering
Indian Institute of Science, Bangalore-560012
*Tel: 080-2293 4094 Email: workshop.cense@iisc.ac.in*

# Program Schedule

## 19th November 2026, Thursday (Online mode – Microsoft Teams)

Link :
Meeting ID: , Passcode:

| *Time* | *Event* |
|---|---|
| ***10:00 AM – 10:30 AM*** | ***Introductory Session*** *– Prof. Sushobhan Avasthi & Ms. Sabiha Sultana* |
| ***10:30 AM – 11:30 AM*** | ***NNfC Safety Protocol*** *– Ms. Shruti Hegde* |
| ***11:30 AM – 12:15 PM*** | ***Introduction to Wet Etch Bay*** *– Dr. Rekha M* |
| ***12:15 PM – 1:00 PM*** | ***Introduction to Furnaces –*** *Ms. Ponnada Sahiti* |

**1:00 PM – 2.00 PM: Lunch Break**

Link :
Meeting ID: , Passcode:

| *Time* | Event |
|---|---|
| ***2:00 PM – 3:00 PM*** | **Introduction to Thin Films** – Mr. Chandan H B |
| ***3:00 PM – 4:00 PM*** | **Introduction to Lithography** – Mr. Ajeya Shettar |
| ***4:00 PM – 4:45 PM*** | **Introduction to Dry Etch** – Ms. Vidyashree K H |
| ***4:45 PM – 5:30 PM*** | **Introduction to MOSFET Module** – Mr. Praveenkumar B H |

## 20th November 2026, Friday (Online mode – Microsoft Teams)

Link :
Meeting ID: , Passcode:

| *Time* | *Event* |
|---|---|
| ***9:30 AM – 10:15 AM*** | ***Introduction to Electrical Characterization*** *– Mr. Arun M* |
| ***10:15 AM – 11:00 AM*** | ***Introduction to AFM*** *– Mr. Vishnuteerth* |
| ***11:00 AM – 12.00 PM*** | ***Introduction to SEM*** *– Dr. Rashmitha Keshava Devadiga* |
| ***12:00 PM – 1.00 PM*** | ***Introduction to FTIR / UV Vis Spectroscopy –*** *Ms. Sinchana R & Ms. Bindhu V* |

**1:00 PM – 2.00 PM: Lunch Break**

Link :
Meeting ID: , Passcode:

| *Time* | Event |
|---|---|
| ***2:00 PM – 3:00 PM*** | **Introduction to FIB** – Dr. Nagabhushan J Choudhari |
| ***3:00 PM – 4:00 PM*** | **Introduction to TEM** – Mr. Ambresh M |

## 23rd November 2026, Monday

| *Time* | *Event* |
|---|---|
| *8:30 AM – 9:00 AM* | ***Registration for the Workshop***<br>*(Ground Floor CeNSE Seminar Hall)* |
| *9:00 AM – 9:30 AM* | ***Briefing & Introductory Session*** |

| *MOSFET – Batch 1*<br>*09:30 AM – 1:00 PM* | *MOSFET - Batch 2*<br>*9:30 AM – 1:00 PM* |
|---|---|
| *Fabrication Session - 1*<br>*RCA*<br>*Oxidation*<br>*Ellipsometer*<br>*(NNFC)* | *Characterization Session - 1*<br>*SEM / FIB*<br>*(MNCF)* |

**1:00 PM – 2.00 PM: Lunch Break** (IDR Building Ground Floor Lunch Area)

| *MOSFET - Batch 1*<br>*2:00 PM – 5:00 PM* | *MOSFET - Batch 2*<br>*2:00 PM – 5:00 PM* |
|---|---|
| *Characterization Session - 1*<br>*SEM / FIB*<br>*(MNCF)* | *Fabrication Session - 1*<br>*RCA*<br>*Oxidation*<br>*Ellipso*<br>*(NNFC)* |

## Holiday – 24th November 2026, Tuesday

## 25th November 2026, Wednesday

| *MOSFET - Batch 1*<br>*9:30 AM – 1:00 PM* | *MOSFET - Batch 2*<br>*9:30 AM – 1:00 PM* |
|---|---|
| *Fabrication Session - 2*<br>*Litho 1*<br>*SiO2 wet etch*<br>*Diffusion*<br>*(NNFC)* | *Characterization Session - 2*<br>*AFM / FTIR / UV-Vis spectroscopy*<br>*(MNCF)* |

**1:00 PM – 2.00 PM: Lunch Break** (IDR Building Ground Floor Lunch Area)

| *MOSFET - Batch 1*<br>*2:00 PM – 5:00 PM* | *MOSFET - Batch 2*<br>*2:00 PM – 5:00 PM* |
|---|---|
| *Characterization Session - 2*<br>*AFM / FTIR / UV-Vis spectroscopy*<br>*(MNCF)* | *Fabrication Session - 2*<br>*Litho 1*<br>*SiO2 wet etch*<br>*Diffusion*<br>*(NNFC)* |

## 26th November 2026, Thursday

| MOSFET - Batch 1<br>9:30 AM – 1:00 PM | MOSFET - Batch 2<br>9:30 AM – 1:00 PM |
|---|---|
| *Fabrication session - 3*<br>*PSG Etch +4PP*<br>*L-2: Litho & SiO2 etch (Background)*<br>*ALD Al2O3 depo/EBE/SPUTTER*<br>*Litho 3 for contact pad opening*<br>*Al2O3 etch*<br>*(NNFC)* | *Characterization Session - 3*<br>*Probe Station 2*<br>*(MNCF)* |

**1:00 PM – 2.00 PM: Lunch Break** (IDR Building 5th floor Lunch Area)

| MOSFET - Batch 1<br>2:00 PM – 5:00 PM | MOSFET - Batch 2<br>2:00 PM – 5:00 PM |
|---|---|
| *Packaging Lab Session 1*<br>*(TCS Smart X Conference Room - 328)*<br>*IDR Building* | *Fabrication session - 3*<br>*PSG Etch +4PP*<br>*L-2: Litho & SiO2 etch (Background)*<br>*ALD Al2O3 depo/EBE/SPUTTER*<br>*Litho 3 for contact pad opening*<br>*Al2O3 etch*<br>*(NNFC)* |

## 27th November 2026, Friday

| *MOSFET - Batch 1*<br>*9:30 AM – 1:00 PM* | *MOSFET - Batch 2*<br>*9:30 AM – 1:00 PM* |
|---|---|
| *Fabrication Session - 4*<br>*Metal dep*<br>*Litho 3 (background)*<br>*Metal dry etch*<br>*Anneal (background)*<br>*(NNFC)* | *Characterization Session - 4*<br>*TEM*<br>*(MNCF)* |

**1:00 PM – 2:00 PM: Lunch Break** (IDR Building 5th Floor Lunch Area)

| *MOSFET - Batch 1*<br>*2:00 PM – 5:00 PM* | *MOSFET - Batch 2*<br>*2:00 PM – 5:00 PM* |
|---|---|
| *Characterization Session - 3*<br>*Probe Station 2*<br>*(MNCF)* | *Fabrication Session - 4*<br>*Metal dep*<br>*Litho 3 (background)*<br>*Metal dry etch*<br>*Anneal (background)*<br>*(NNFC)* |

## Holiday – 28th November 2026, Saturday
## Holiday – 29th November 2026, Sunday

## 30th November 2026, Monday

| | |
|---|---|
| ***MOSFET - Batch 1***<br>***9:30 AM – 1:00 PM*** | ***MOSFET - Batch 2***<br>***9:30 AM – 1:00 PM*** |
| ***Lab Visit:***<br>***Gas Sensor Lab***<br>***(Second Floor SF-31)*** | ***Packaging Lab Session 1***<br>***(Third Floor TF-32)*** |

**1:00 PM – 2:00 PM: Lunch Break** (IDR Building Ground Floor Lunch Area)

| | |
|---|---|
| ***MOSFET - Batch 1***<br>***2:00 PM – 5:00 PM*** | ***MOSFET - Batch 2***<br>***2:00 PM – 5:00 PM*** |
| ***Packaging Lab Session 2***<br>***(Third Floor TF-32)*** | ***Lab Visit:***<br>***Gas Sensor Lab***<br>***(Second Floor SF-31)*** |

## 1st December 2026, Tuesday

| | |
|---|---|
| ***MOSFET - Batch 1***<br>***9:30 AM – 1:00 PM*** | ***MOSFET - Batch 2***<br>***9:30 AM – 1:00 PM*** |
| ***Characterization Session - 4***<br>***TEM***<br>***(MNCF)*** | ***Packaging Lab Session 2***<br>***(Third Floor TF-32)*** |

**1:00 PM – 2:00 PM: Lunch Break** (IDR Building Ground Floor Lunch Area

| | |
|---|---|
| ***MOSFET - Batch 1***<br>***2:00 PM – 4:00 PM*** | **MOSFET - Batch 2**<br>**2:00 PM – 4:00 PM** |
| ***Presentation by participants***<br>*(Ground Floor CeNSE Seminar Hall)* | **Presentation by participants**<br>(Ground Floor CeNSE Seminar Hall) |

| ***Time*** | **Event** |
|---|---|
| ***4:00 PM – 4.15 PM*** | **Hi-Tea** |
| ***4:15 PM – 5.00 PM*** | **Fabrication & Characterization Quiz Session**<br>Ground Floor CeNSE Seminar Hall |
| ***5:00 PM – 5:30 PM*** | **Feedback, Valedictory & Concluding Session**<br>(Ground Floor CeNSE Seminar Hall) |